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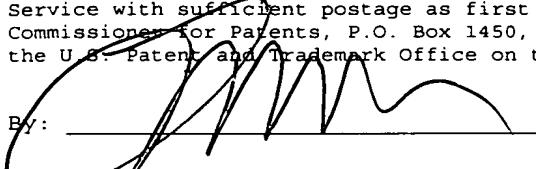
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By: 

Date: September 22, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 09/873,230 Confirmation No. 4487

Applicant : Norbert Benesch et al.

Filed : June 4, 2001

TC/A.U. : 2625

Examiner : John B. Strege

Title: : Method and Device for Optically Monitoring
Fabrication Processes of Finely Structured
Surfaces in a Semiconductor Production

Docket No. : EHF 2001,0167 P

Customer No. : 24131

Hon. Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office action dated June 23, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 15 of this paper.